



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of: **Hitoshi YAMADA et al.**

Group Art Unit: **1762**

Application Number: **10/642,271**

Examiner: **Marianne L. Padgett**

Filed: **August 18, 2003**

Confirmation Number: **2420**

For: **METHOD OF FORMING METAL OXIDE FILM AND METHOD  
FOR FORMING SECONDARY ELECTRON EMISSION FILM IN  
GAS DISCHARGE TUBE**

Attorney Docket Number: **030933**  
Customer Number: **38834**

**AMENDMENT UNDER 37 C.F.R. § 1.111**

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

October 6, 2006

Sir:

In response to the Office Action dated July 6, 2006, Applicants amend the claims as follows and submit the following remarks.

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 4 of this paper.